





## INVESTIGATION OF ELECTRICAL CHARACTERISTICS AND SURFACE MORPHOLOGY OF VANADIUM OXIDE-VO<sub>2</sub> MOS DEVICES

Umutcan GURER<sup>1,2</sup> and Ercan YILMAZ<sup>1,2,\*</sup>

<sup>1</sup> Nuclear Radiation Detectors Application and Research Center, BAIBU, 14030 Bolu, TURKEY
<sup>2</sup> Physics Department, Bolu Abant Izzet Baysal University, 14030 Bolu, TURKEY

06-10 July 2020, RAP 2020

# **Content Outline**

- Introduction
- Experimental Details
- XRD Analysis Results
- FTIR Analysis Results
- Electrical Characterization Results

2

Conclusion







#### Introduction

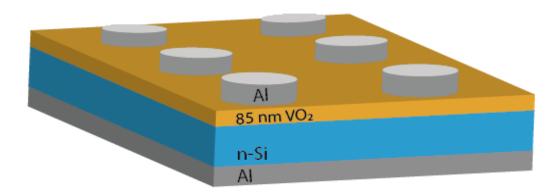
- ✤ Vanadium dioxide is well known for the semiconductor-metal phase transition at 67°C.
- ♦ Vanadium Oxide is also known to exist in multiple oxidation states (like +4 in VO<sub>2</sub> and +5 in V<sub>2</sub>O<sub>5</sub>).
- An increasing interest has been devoted to hybrid vanadium oxides due to their potential application as catalysts, sensors, and electrodes during the last years.
- Our goal; preliminary work of investigation of electrical and surface morphology of vanadium oxide for the application in MOS devices and MOSFET in radiation environment.







#### **Experimental Details**



- ✤ VO<sub>2</sub> thin films with thickness of 85 nm were deposited on n-type silicon (100) substrate by using RF Magnetron Sputtering System.
- ✤ After deposition, samples annealed at 100 °C, 300 °C, 500 °C and 700°C under Ar ambient with Rapid Thermal Annealing (RTA) system.

4

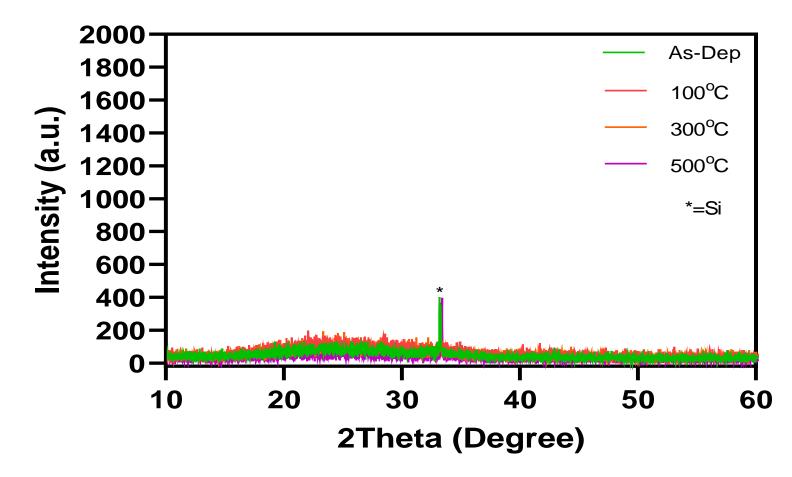
- Electrical characterization were done by analyzing C-V and G/w-V @ 1 MHz.
- Surface Morphology was investigated by analyzing XRD measurements.
- ✤ Bond structures investigated by analyzing ATR-FTIR measurements.







#### XRD (X-Ray Diffraction) Analysis Results



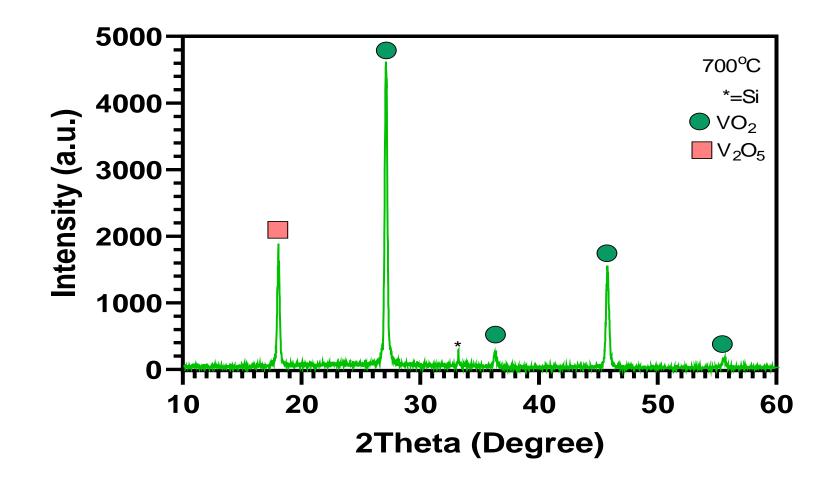
• As-deposited and the samples annealed at 100°C, 300°C and 500°C showed amorphous structure.





#### XRD Analysis Results

• The sample annealed @700°C showed polycrystalline structure.

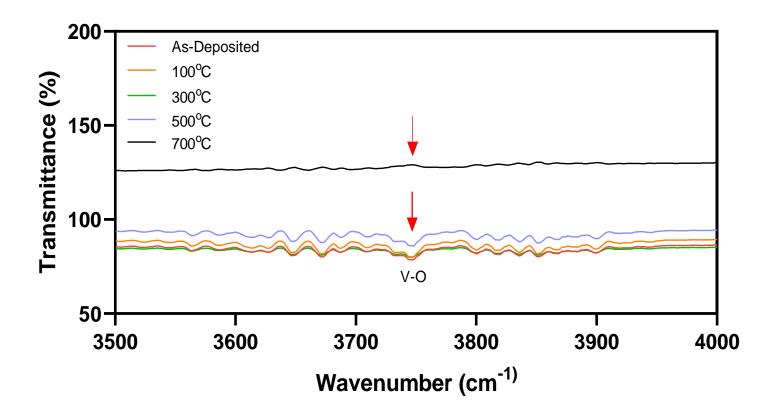






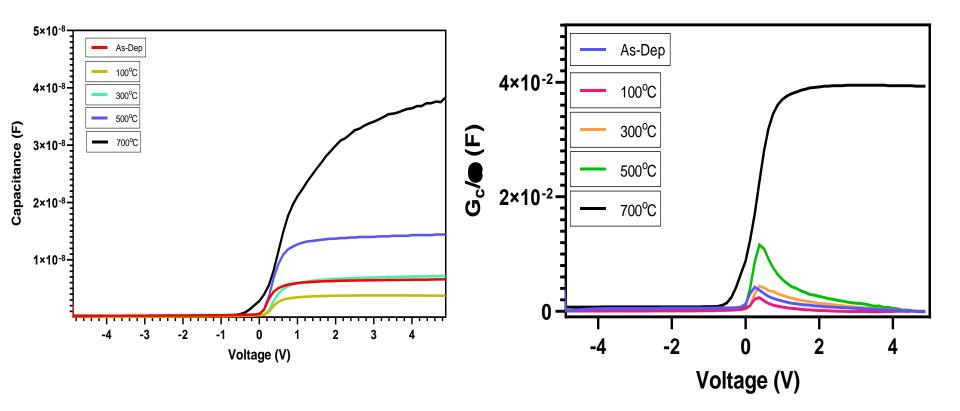
#### FTIR Analysis Results

- The presence of peak at 3745 cm<sup>-1</sup> belongs to V-O bonds.
- The peak at 3745 cm<sup>-1</sup> was missing due to annealing temperature.





#### **Electrical Characterization Results**



• The capacitance and conductance values showed increasing trend with the increasing annealing temperature.





### **Conclusion**

- XRD measurements showed that annealing had major effect on crystallanity on VO<sub>2</sub> thin films structures. Also, the polycrystalline structure has been found in 700°C annealed samples.
- The annealing  $>700^{\circ}$ C has increased crystallinity of VO<sub>2</sub>.
- ATR-FTIR measurements revealed that V-O bond has been found on thin film structures @ 3974 cm<sup>-1</sup> wavenumber.
- The C-V and G/w-V analyses showed increasing trend with the increasing annealing.

#### <u>Acknowledgements:</u>

This work is supported by the Presidency of Turkey, Presidency of Strategy and Budget under Contract Number: 2016K12-2834.







# **Thanks for Your Attention**







